

CLAIMS:

1. A method of facilitating a process performed by a semiconductor processing tool, comprising:

inputting data relating to a process performed by the semiconductor processing tool;

inputting a first principles physical model relating to the semiconductor processing tool;

performing first principles simulation using the input data and the physical model to provide a simulation result for the process performed by the semiconductor processing tool; and

using the simulation result as part of a data set that characterizes the process performed by the semiconductor processing tool.

2. The method of Claim 1, wherein said inputting comprises directly inputting the data relating to a process performed by the semiconductor processing tool from at least one of a physical sensor and a metrology tool physically mounted on the semiconductor processing tool.

3. The method of Claim 1, wherein said inputting comprises indirectly inputting the data relating to a process performed by the semiconductor processing tool from at least one of a manual input device and a database.

4. The method of Claim 3, wherein said indirectly inputting comprises inputting data recorded from a process previously performed by the semiconductor processing tool.

5. The method of Claim 3, wherein said indirectly inputting comprises inputting data set by a simulation operator.

6. The method of Claim 1, wherein said inputting comprises inputting the data relating to a process performed by the semiconductor processing tool as virtual sensor data from a simulation module.

7. The method of Claim 1, wherein said inputting data comprises inputting data relating to at least one of the physical characteristics of the semiconductor processing tool and the semiconductor tool environment.

8. The method of Claim 1, wherein said inputting data comprises inputting data relating to at least one of a characteristic and a result of a process performed by the semiconductor processing tool.

9. The method of Claim 1, wherein said inputting a first principles physical model comprises inputting a spatially resolved model of the geometry of the semiconductor processing tool.

10. The method of Claim 1, wherein said inputting a first principles physical model comprises inputting fundamental equations necessary to perform first principles simulation to obtain a simulation result that can form part of a data set that characterizes the process performed by the semiconductor processing tool.

11. The method of Claim 1, wherein said performing first principles simulation comprises performing first principles simulation concurrently with the process performed by the semiconductor processing tool.

12. The method of Claim 11, wherein said performing first principles simulation comprises performing first principles simulation to provide a simulation result that is a variation of a parameter tested by the concurrent process performed by the semiconductor processing tool.

13. The method of Claim 11, wherein said performing first principles simulation comprises performing first principles simulation to provide a simulation result relating to a different parameter than a parameter tested by the concurrent process performed by the semiconductor processing tool.

14. The method of Claim 1, wherein said performing first principles simulation comprises performing first principles simulation not concurrently with the process performed by the semiconductor processing tool.

15. The method of Claim 1, further comprising storing the data set in a library for subsequent use processes performed by the semiconductor processing tool.

16. The method of Claim 1, further comprising using a network of interconnected resources to perform at least one of the process steps recited in Claim 1.

17. The method of Claim 16, further comprising using code parallelization among interconnected computational resources to share the computational load of the first principles simulation.

18. The method of Claim 16, further comprising sharing simulation information among interconnected resources to facilitate a process performed by the semiconductor processing tool.

19. The method of Claim 18, wherein said sharing simulation information comprises distributing simulation results among the interconnected resources to reduce redundant execution of substantially similar first principles simulations by different resources.

20. The method of Claim 18, wherein said sharing simulation information comprises distributing model changes among the interconnected resources to reduce redundant refinements of first principles simulations by different resources.

21. The method of Claim 18, further comprising using remote resources via a wide area network to facilitate the semiconductor process performed by the semiconductor processing tool.

22. The method of Claim 21, wherein said using remote resources comprises using at least one of remote computational and storage resources via a wide area network to facilitate the semiconductor process performed by the semiconductor processing tool.

23. A system comprising:
a semiconductor processing tool configured to perform a process;
an input device configured to input data relating to the process performed by the semiconductor processing tool; and
a first principles simulation processor configured to:
input a first principles physical model relating to the semiconductor processing tool, and
perform first principles simulation using the input data and the physical model to provide a first principles simulation result for the process performed by the semiconductor processing tool, wherein the simulation result is used as part of a data set that characterizes the process performed by the semiconductor processing tool.

24. The system of Claim 23, wherein said input device comprises at least one of a physical sensor and a metrology tool physically mounted on the semiconductor processing tool.

25. The system of Claim 23, wherein said input device comprises at least one of a manual input device and a database.

26. The system of Claim 25, wherein said input device is configured to input data recorded from a process previously performed by the semiconductor processing tool.

27. The system of Claim 25, wherein said input device is configured to input data set by a simulation operator.

28. The system of Claim 23, wherein said input device is configured to input the data relating to a process performed by the semiconductor processing tool as virtual sensor data from a simulation module.

29. The system of Claim 23, wherein said input device is configured to input data relating to at least one of the physical characteristics of the semiconductor processing tool and the semiconductor tool environment.

30. The system of Claim 23, wherein said input device is configured to input data relating to at least one of a characteristic and a result of a process performed by the semiconductor processing tool.

31. The system of Claim 23, wherein said processor is configured to input a first principles physical model comprising a spatially resolved model of the geometry of the semiconductor processing tool.

32. The system of Claim 23, wherein said processor is configured to input a first principles physical model comprising fundamental equations necessary to perform first principles simulation to obtain a simulation result that can form part of a data set that characterizes the process performed by the semiconductor processing tool.

33. The system of Claim 23, wherein said processor is configured to perform said first principles simulation concurrently with the process performed by the semiconductor processing tool.

34. The system of Claim 33, wherein said processor is configured to perform the first principles simulation to provide a simulation result that is a variation of a parameter tested by the concurrent process performed by the semiconductor processing tool.

35. The system of Claim 33, wherein said processor is configured to perform the first principles simulation to provide a simulation result relating to a different parameter than a parameter tested by the concurrent process performed by the semiconductor processing tool.

36. The system of Claim 23, wherein said processor is configured to perform said first principles simulation not concurrently with the process performed by the semiconductor processing tool.

37. The system of Claim 23, wherein said processor is further configured to store the data set in a library for subsequent use processes performed by the semiconductor processing tool.

38. The system of Claim 23, further comprising a network of interconnected resources connected to said processor and configured to assist said processor in performing at least one of the inputting a first principles simulation model and performing a first principles simulation.

39. The system of Claim 38, wherein said network of interconnected resources is configured to use code parallelization with said processor to share the computational load of the first principles simulation.

40. The system of Claim 38, wherein said network of interconnected resources is configured to share simulation information with said processor to facilitate said process performed by the semiconductor processing tool.

41. The system of Claim 40, wherein said network of interconnected resources is configured to distribute simulation results to said processor to reduce redundant execution of substantially similar first principles simulations.

42. The system of Claim 40, wherein said network of interconnected resources is configured to distribute model changes to said processor to reduce redundant refinements of first principles simulations.

43. The system of Claim 38, further comprising remote resources connected to said processor via a wide area network and configured to facilitate the semiconductor process performed by the semiconductor processing tool.

44. The system of Claim 43, wherein said remote resources comprise at least one of a computational and a storage resource.

45. A system for facilitating a process performed by a semiconductor processing tool, comprising:

means for inputting data relating to a process performed by the semiconductor processing tool;

means for inputting a first principles physical model relating to the semiconductor processing tool;

means for performing first principles simulation using the input data and the physical model to provide a simulation result for the process performed by the semiconductor processing tool; and

means for using the simulation result as part of a data set that characterizes the process performed by the semiconductor processing tool.

46. The system of Claim 43, further comprising means for sharing the computational load of the first principles simulation.

47. The system of Claim 43, further comprising means for sharing simulation information among interconnected resources to facilitate a process performed by the semiconductor processing tool.

48. A computer readable medium containing program instructions for execution on a processor, which when executed by the computer system, cause the processor to perform the steps of:

inputting data relating to a process performed by the semiconductor processing tool;
inputting a first principles physical model relating to the semiconductor processing tool;

performing first principles simulation using the input data and the physical model to provide a simulation result for the process performed by the semiconductor processing tool;
and

using the simulation result as part of a data set that characterizes the process performed by the semiconductor processing tool.